

Title (en)

TOP-PORT MEMS MICROPHONE WITH REDUCED MECHANICAL LOADS AS WELL AS A MANUFACTURING PROCESS

Title (de)

MEMS-MIKROFON MIT OBEN ANGEORDNETER SCHALLÖFFNUNG UND VERRINGERTEN MECHANISCHEN BELASTUNGEN UND VERFAHREN ZUR HERSTELLUNG

Title (fr)

MICROPHONE À MEMS AVEC UNE OUVERTURE SONORE SUPÉRIEURE ET AVEC DES CONTRAINTES MÉCANIQUES RÉDUITES AINSI QU' UN PROCÉDÉ DE PRODUCTION

Publication

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Application

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Priority

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Abstract (en)

[origin: WO2018108482A1] The invention relates to a MEMS microphone having good acoustic properties and a reduced failure probability due to faulty electrical connections. For this purpose, the microphone has a channel that connects a sound opening to a MEMS chip. The channel comprises a heterogeneous material from two different components which have different thermal properties.

IPC 8 full level

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CPC (source: EP)

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Citation (examination)

- DE 102011087963 A1 20120614 - BOSCH GMBH ROBERT [DE]
- EP 3329690 A1 20180606 - EPCOS AG [DE]
- US 3615972 A 19711026 - MOREHOUSE DONALD S JR, et al
- DE 102011080142 A1 20130131 - ENDRESS & HAUSER GMBH & CO KG [DE], et al

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